

Super Short or Super Small: Exploring the Limits of Laser Microprocessing with Industrial Grade Systems

B. Neuenschwander

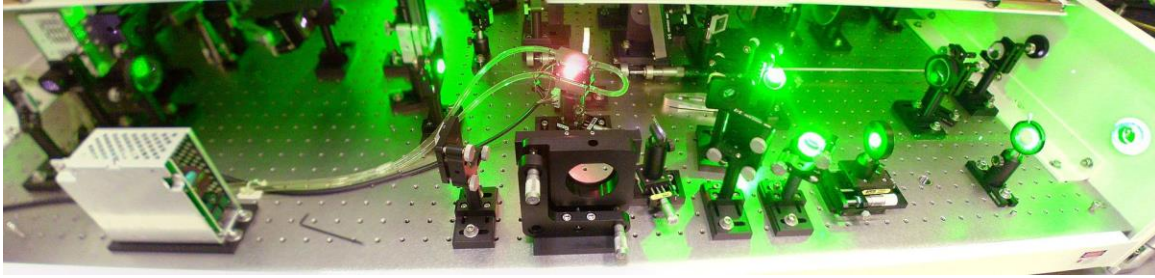
► Institute for Applied Laser, Photonics and Surface Technologies ALPS



Berner Fachhochschule
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Bern University of Applied Sciences

Super Short

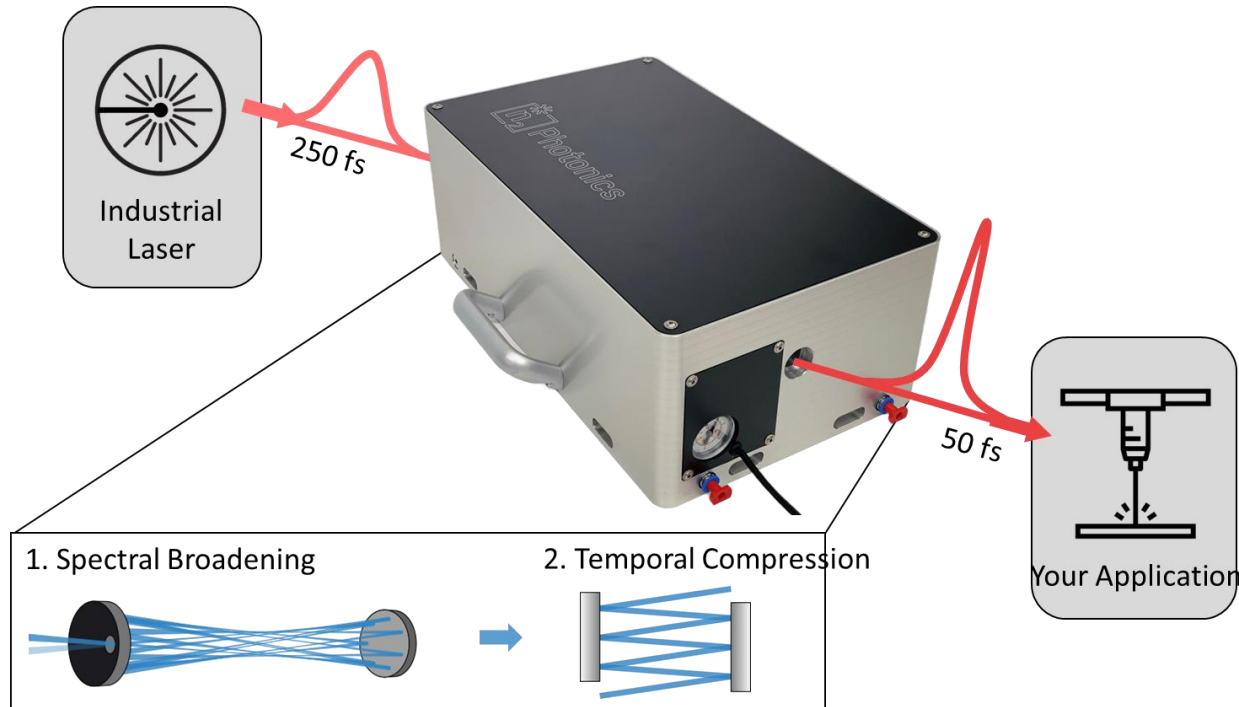
Motivation: Sub-100 fs Pulses



[ODIN Ti-Sapphire laser in operation - Ti-sapphire laser - Wikipedia](#)

- ▶ For long time the sub 100 fs regime was only accessible with Ti:Sapphire laser systems.
- ▶ They have the reputation to be complicate to operate and "demanding a physicist to drive them".

Motivation: Sub-100 fs Pulses



MIKS1_S | n2 Photonics (n2-photonics.de)

- ▶ For long time the sub 100 fs regime was only accessible with Ti:Sapphire laser systems.
- ▶ They have the reputation to be complicated to operate and "demanding a physicist to drive them".
- ▶ New devices allow to broaden the spectrum of industrial grade ultrashort pulsed laser systems to access the regime of sub 100 fs pulses for industrial micro-processing.
- ▶ Explore the sub 100 fs regime in an explorative study.

Experimental Set-Up IR Pulse Shortening

- ▶ Pharos PH1-15-0400-02-30

- ▶ $\Delta\tau = 270 \text{ fs}$

- ▶ $\lambda = 1030 \text{ nm}$

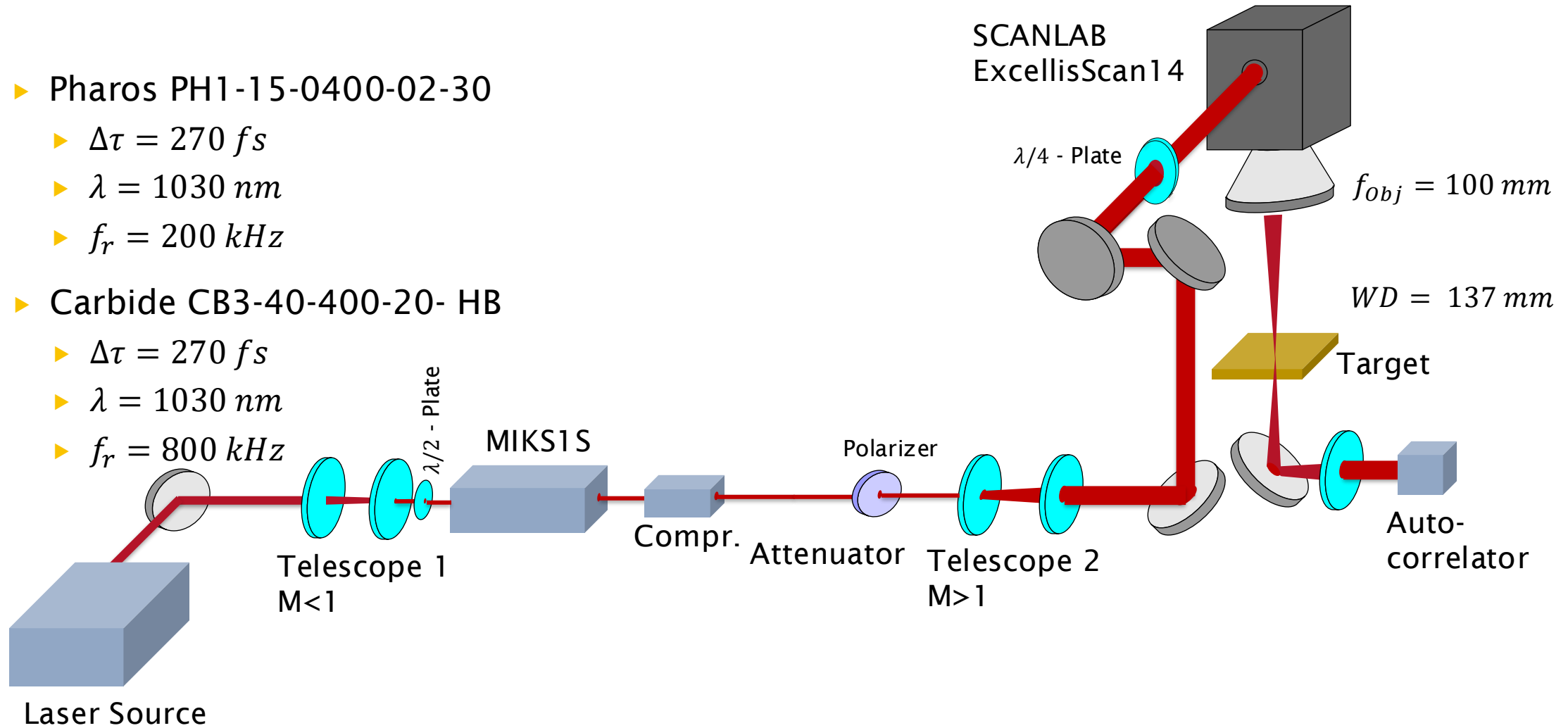
- ▶ $f_r = 200 \text{ kHz}$

- ▶ Carbide CB3-40-400-20- HB

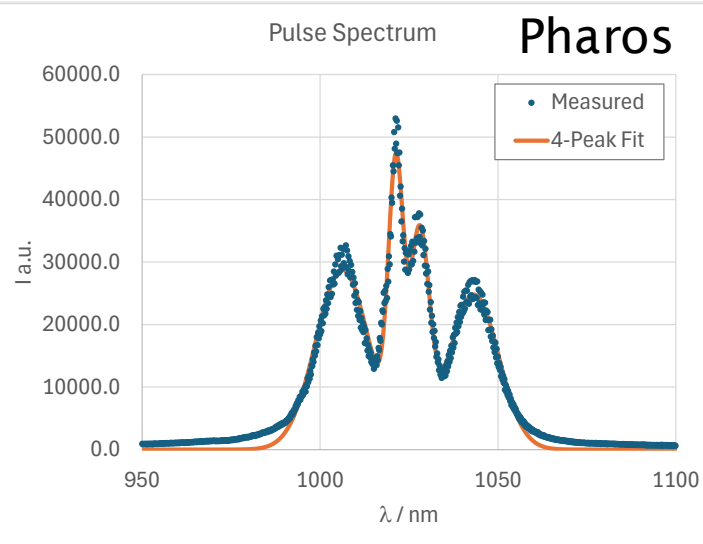
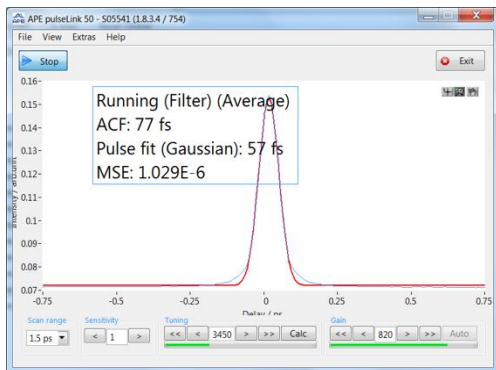
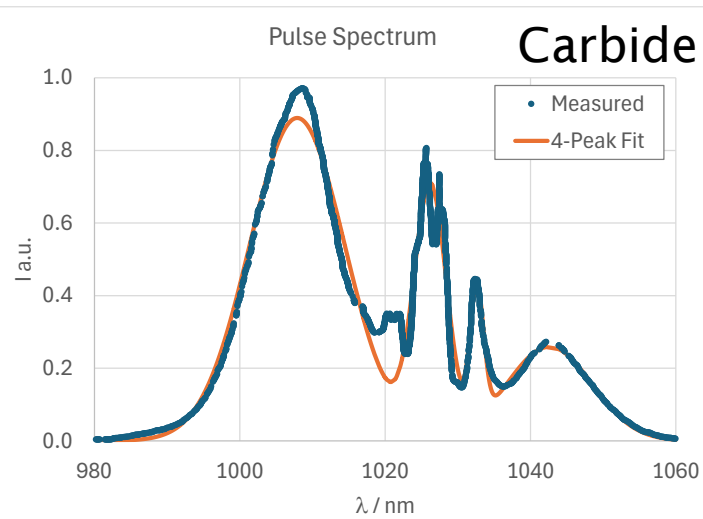
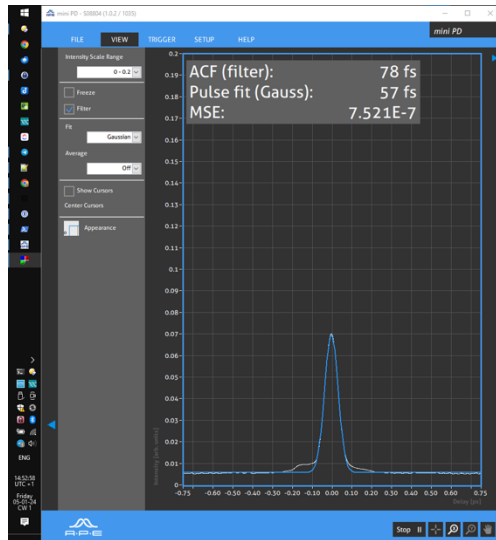
- ▶ $\Delta\tau = 270 \text{ fs}$

- ▶ $\lambda = 1030 \text{ nm}$

- ▶ $f_r = 800 \text{ kHz}$

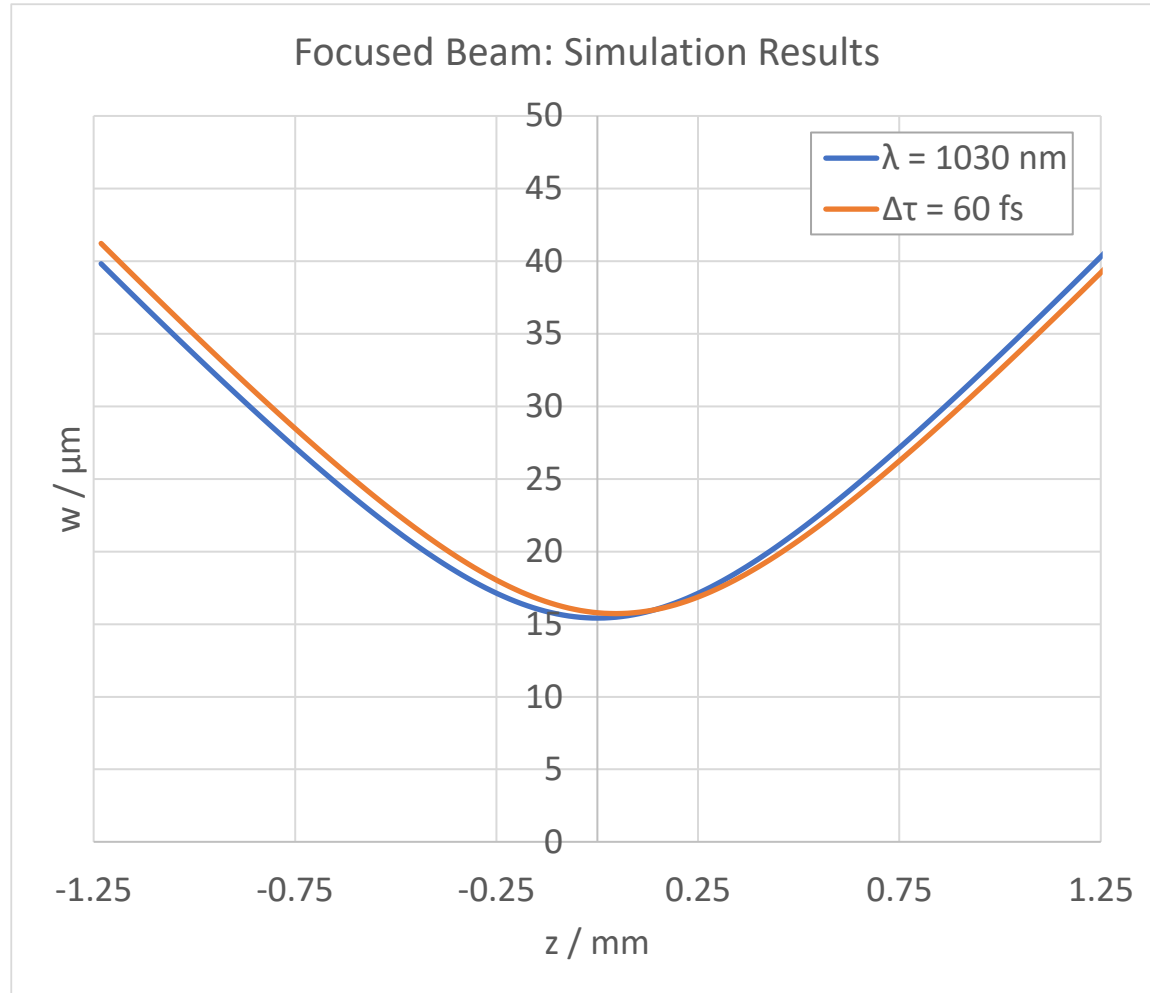


Autocorrelator Trace and Spectrum after Objective



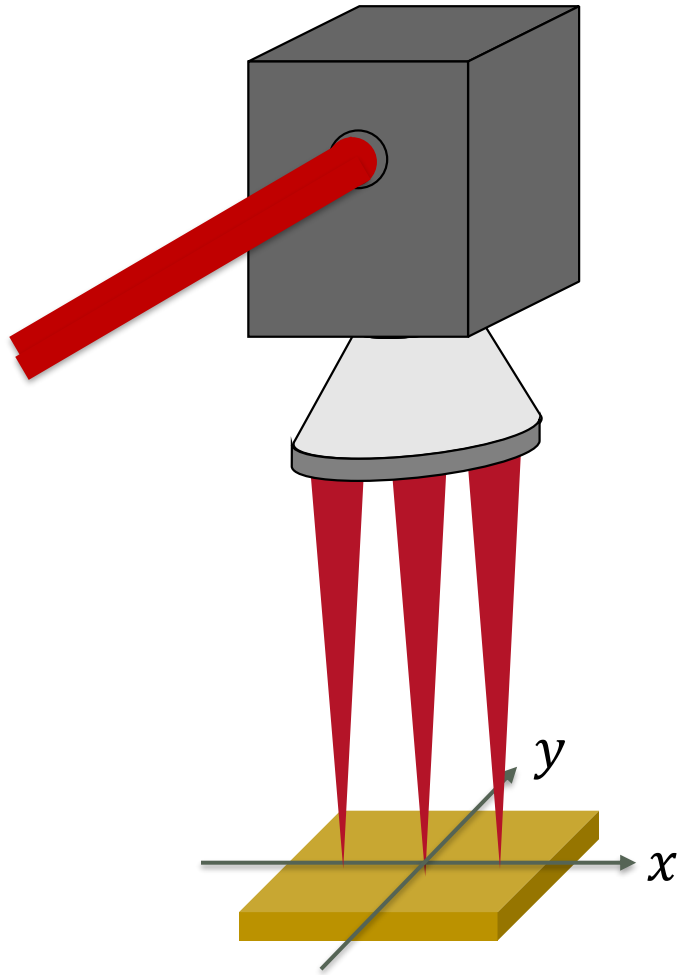
- ▶ $\Delta\tau_{min} \approx 57 fs$
- ▶ $w_0 \approx 15 \mu m$
- ▶ $M^2 \approx 1.5$
- ▶ Circular polarized
- ▶ Spot size and position independent on
 - ▶ Pulse duration
 - ▶ Pulse energy
- ▶ Due to chromatic dispersion
 - ▶ Each wavelength is focused at different positions.
 - ▶ Waist radii $w_0(\lambda)$ will also slightly differ.
- ▶ Could this lead to an elongated focus?

Influence of Chromatic Dispersion on Focusing



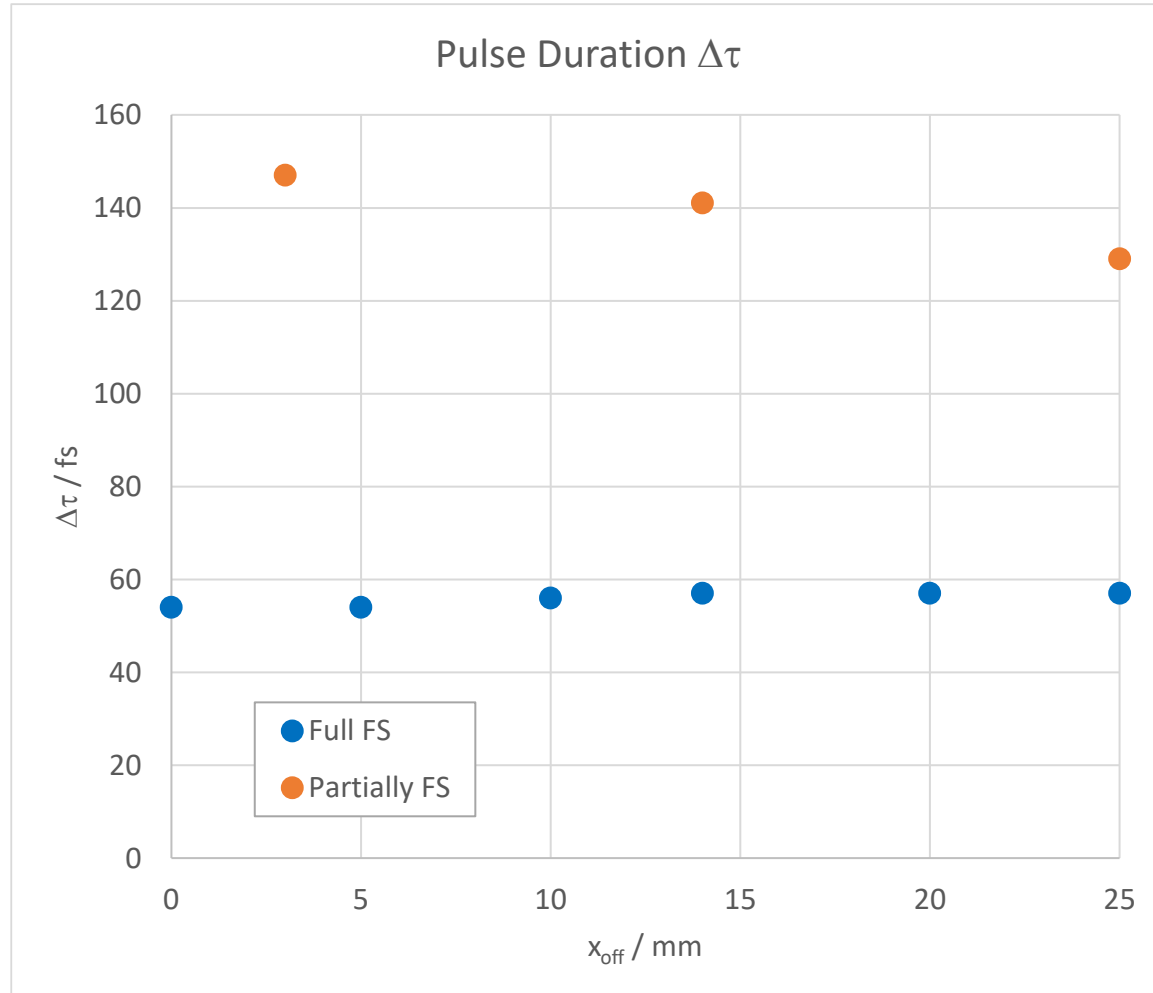
- ▶ Fitted parameters:
 - ▶ $\lambda = 1030 \text{ nm}$:
 $w_0 = 15.4 \mu\text{m}, M^2 = 1.4$
 - ▶ $\Delta\tau = 60 \text{ fs}$, broad spectrum (Pharos):
 $w_0 = 15.7 \mu\text{m}, M^2 = 1.43, d_{off} = 45 \mu\text{m}$
- ▶ Focal position of 60 fs beam is shifted by $45 \mu\text{m}$ from objective away
- ▶ Spot size gets a little bigger $\approx 2 \%$
- ▶ Slightly higher M^2
- ▶ No elongated focus

Chromatic Dispersion and Beam Deflection



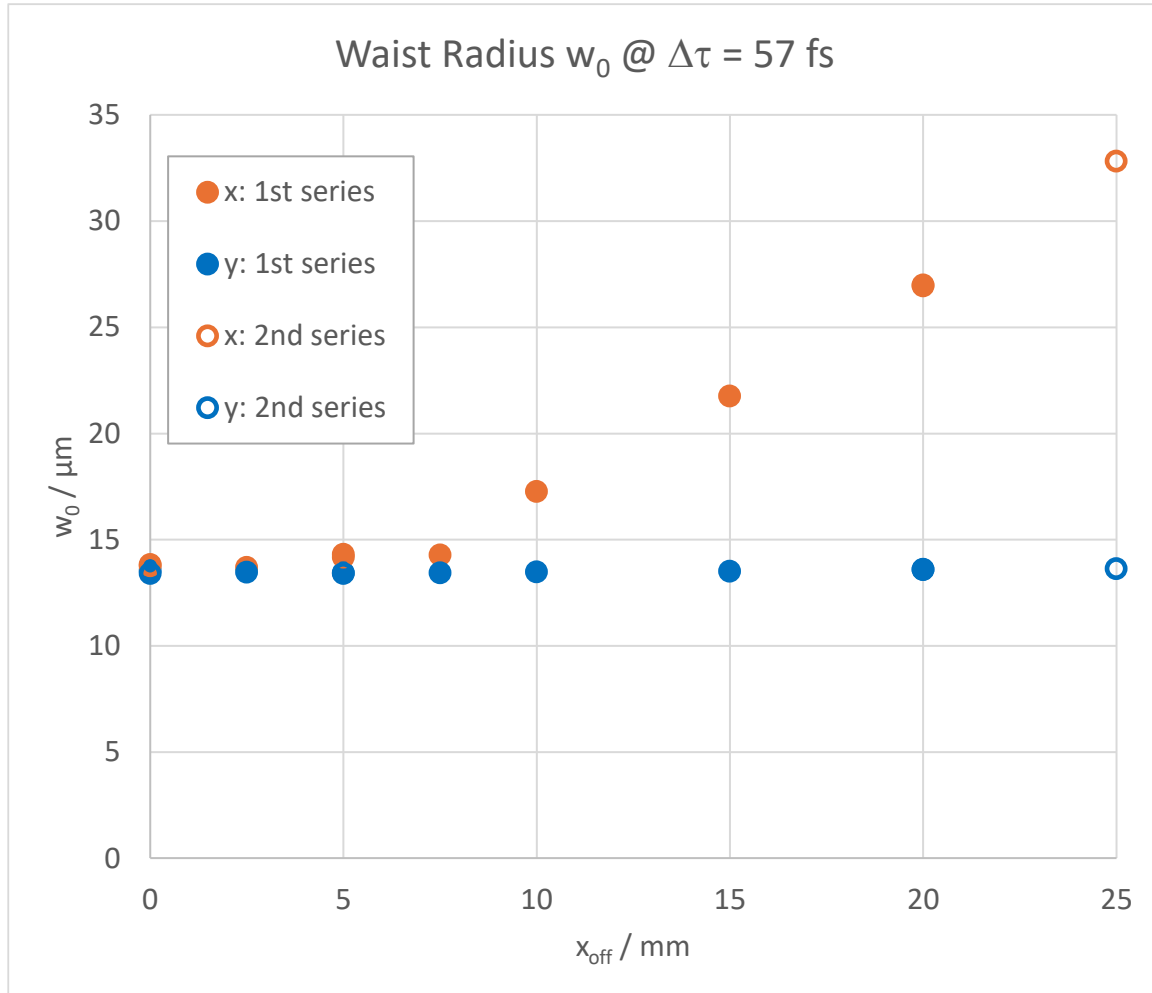
- ▶ Will beam deflection lead to beam distortion due to chromatic dispersion?
- ▶ Deflect the beam in x-direction and measure beam caustic and pulse duration.

Pharos: Influence on the Beam Deflection



- ▶ The pulse duration for the full-FS objective rests unaffected.
- ▶ Dispersion not compensated for partially FS objective.

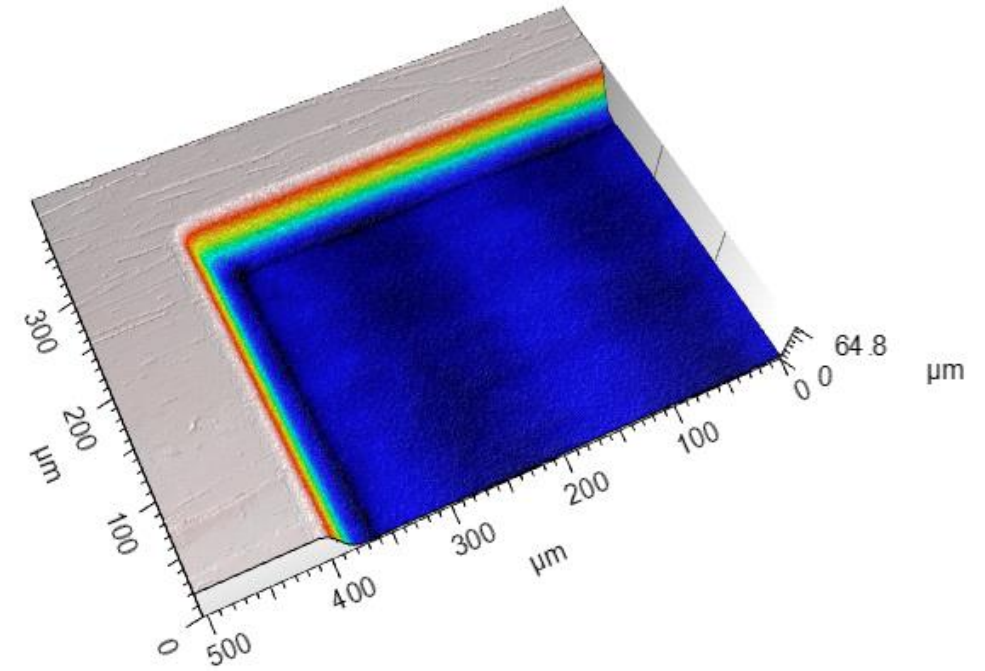
Pharos: Influence on the Beam Deflection



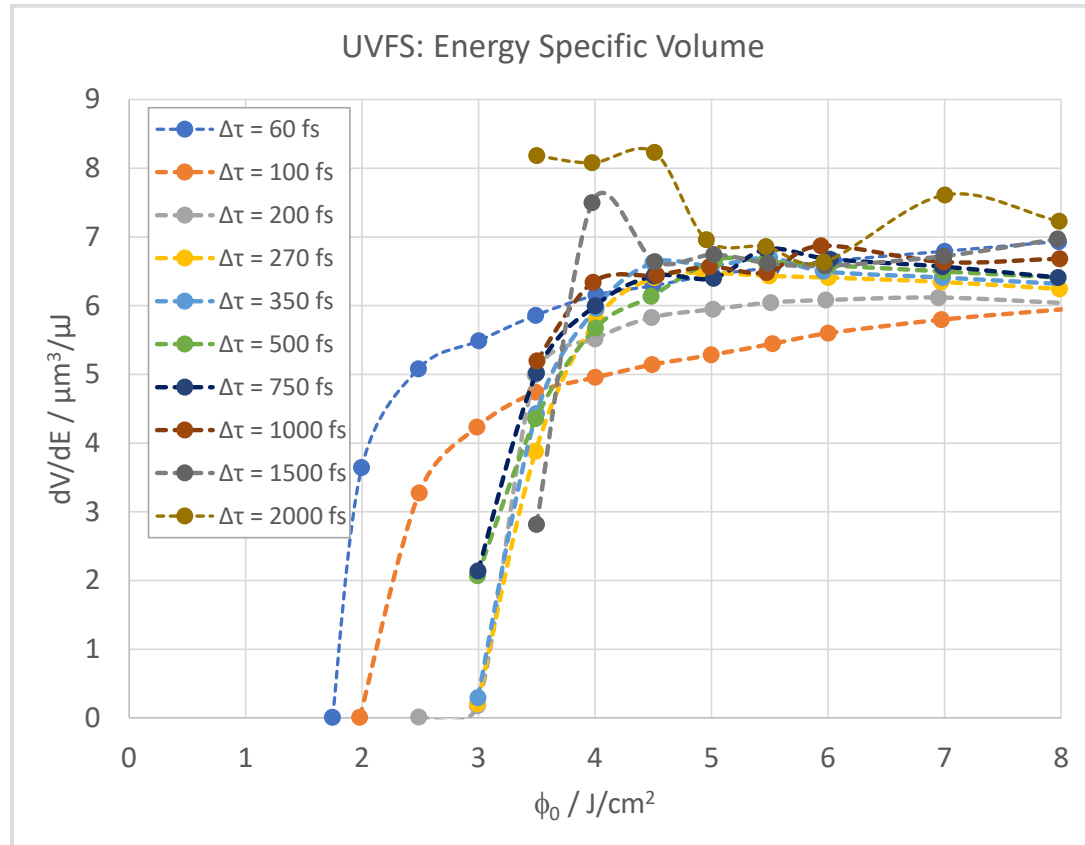
- ▶ The pulse duration for the full-FS objective rests unaffected.
- ▶ Dispersion not compensated for partially FS objective.
- ▶ Waist in x-direction (offset direction) significantly increase for $x_{\text{off}} > 7.5$ mm.
- ▶ For the y-direction (perpendicular to the offset) the waist radius is unaffected.
- ▶ Identical behavior for beam quality M^2 .
- ▶ For short pulses ($\Delta\tau < 500$ fs) the scan-field should be limited from ± 24 mm to ± 5 mm for the $f = 100$ mm Objective.

Experimental Procedure

- ▶ f_r fixed to 800 kHz respectively 200 kHz and peak fluence increased from the threshold to several J/cm^2 .
- ▶ Squares of side length $s = 1\text{ mm}$ machined with spot and line distance $p_x = p_y = 5\text{ }\mu\text{m}$ and a fixed number of pulses per area.
- ▶ Depth d measured with either a white light interferometric microscope (WLI) or a confocal laser scanning microscope (LSM).
- ▶ Energy specific volume γ given by:
$$\gamma = \left(\frac{dV}{dt}\right) / P_{av} = \frac{dV}{dE} = \frac{s^2 \cdot d}{dt \cdot P_{av}} = \frac{d \cdot p_x \cdot p_y \cdot f_r}{N_{Sl} \cdot P_{av}}$$
- ▶ Surface roughness deduced following ISO 25178.

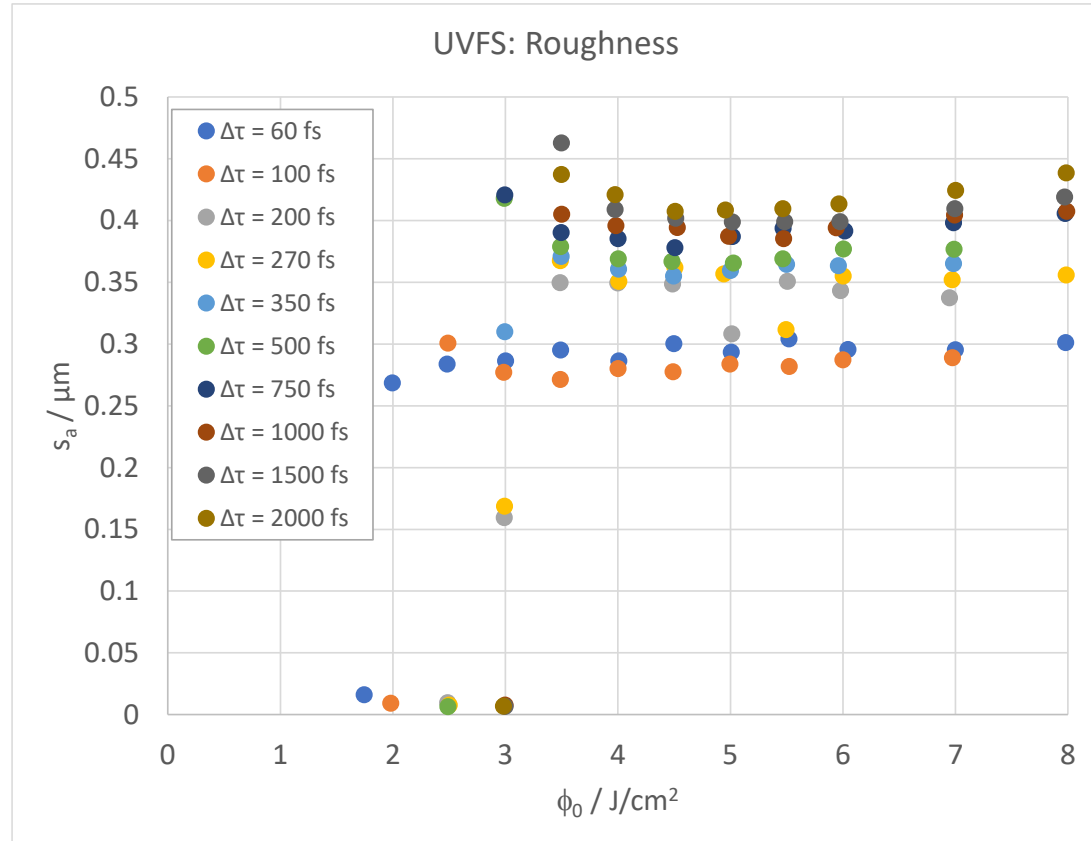


Carbide: UV Grade Fused Silica



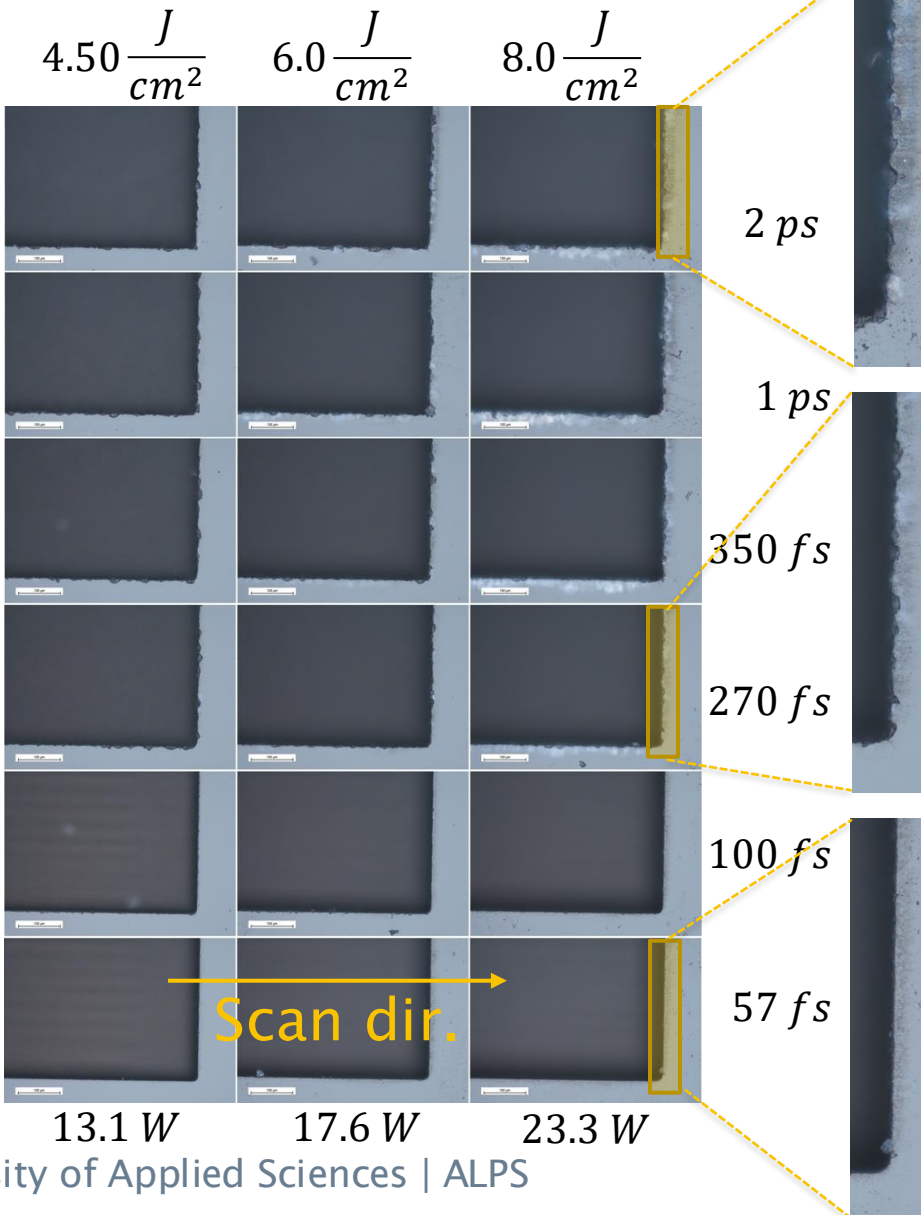
- ▶ With decreasing pulse duration energy specific volume first drops ($\Delta\tau = 100$ fs) and then increases again for $\Delta\tau = 57$ fs.
- ▶ Significantly reduced threshold for $\Delta\tau = 57$ fs and $\Delta\tau = 100$ fs.

Carbide: UV Grade Fused Silica



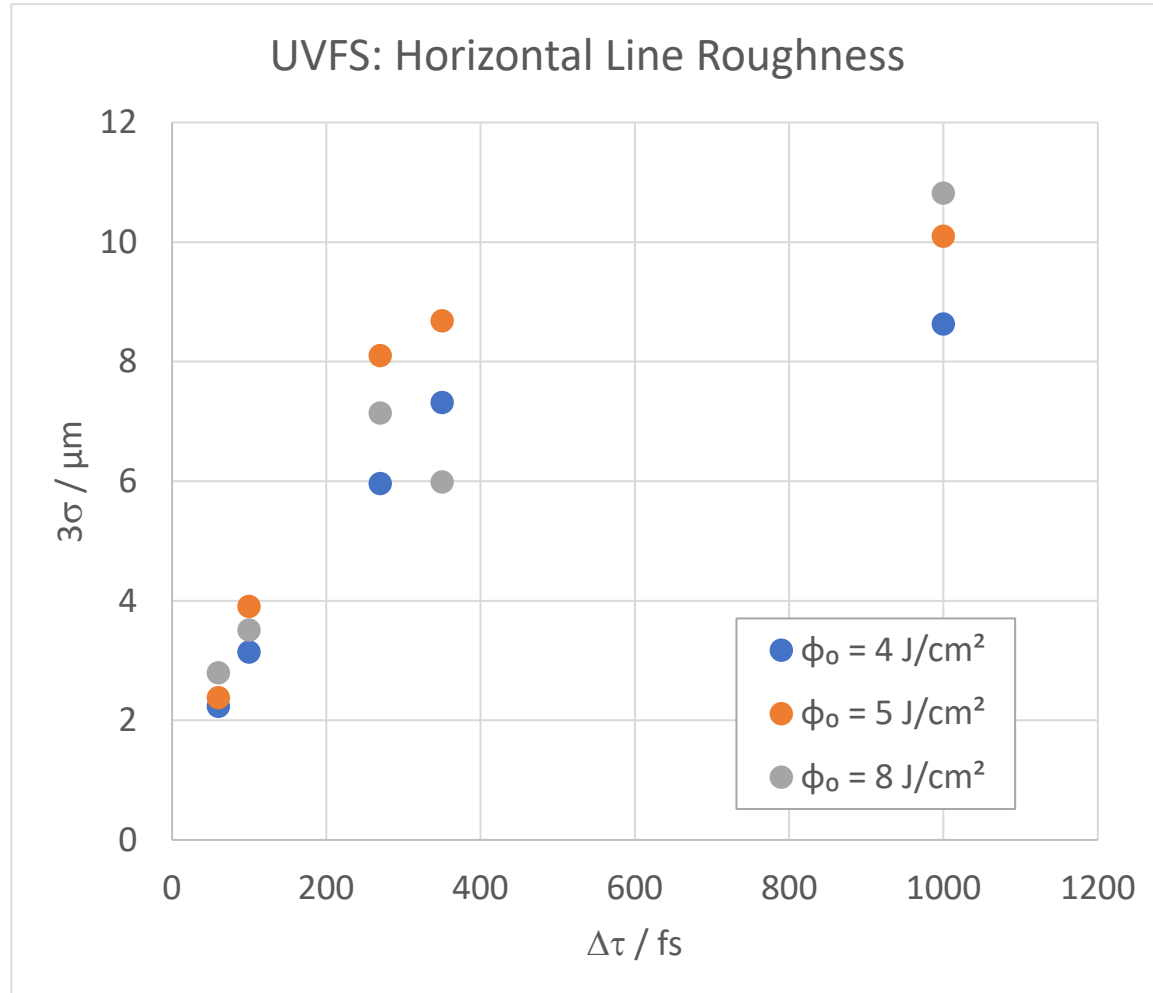
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- ▶ Significantly reduced threshold for $\Delta\tau = 57$ fs and $\Delta\tau = 100$ fs.
- ▶ Roughness of the process stays almost constants for peak fluences above the threshold.
- ▶ Smaller for $\Delta\tau = 57$ fs and $\Delta\tau = 100$ fs.

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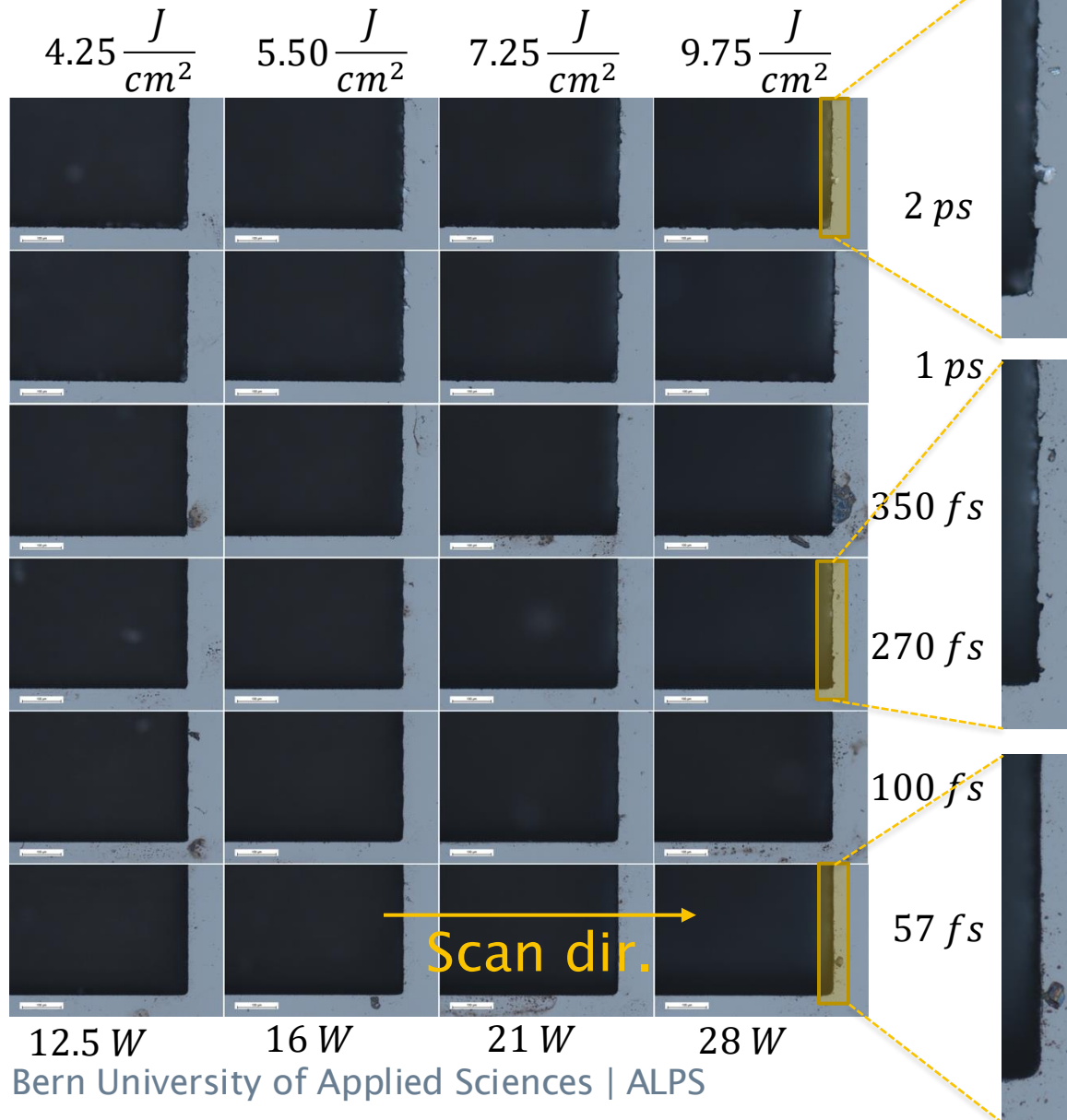
- ▶ With decreasing pulse duration energy specific volume first drops ($\Delta\tau = 100 fs$) and then increases again for $\Delta\tau = 57 fs$.
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- ▶ Smaller for $\Delta\tau = 57 fs$ and $\Delta\tau = 100 fs$.
- ▶ Edge quality massively improved for shorter pulse durations $\Delta\tau = 57 fs$ and $\Delta\tau = 100 fs$.
- ▶ No visible chipping for $\Delta\tau = 57 fs$ and $P_{av} = 23.3 W$.

Carbide: UV Grade Fused Silica



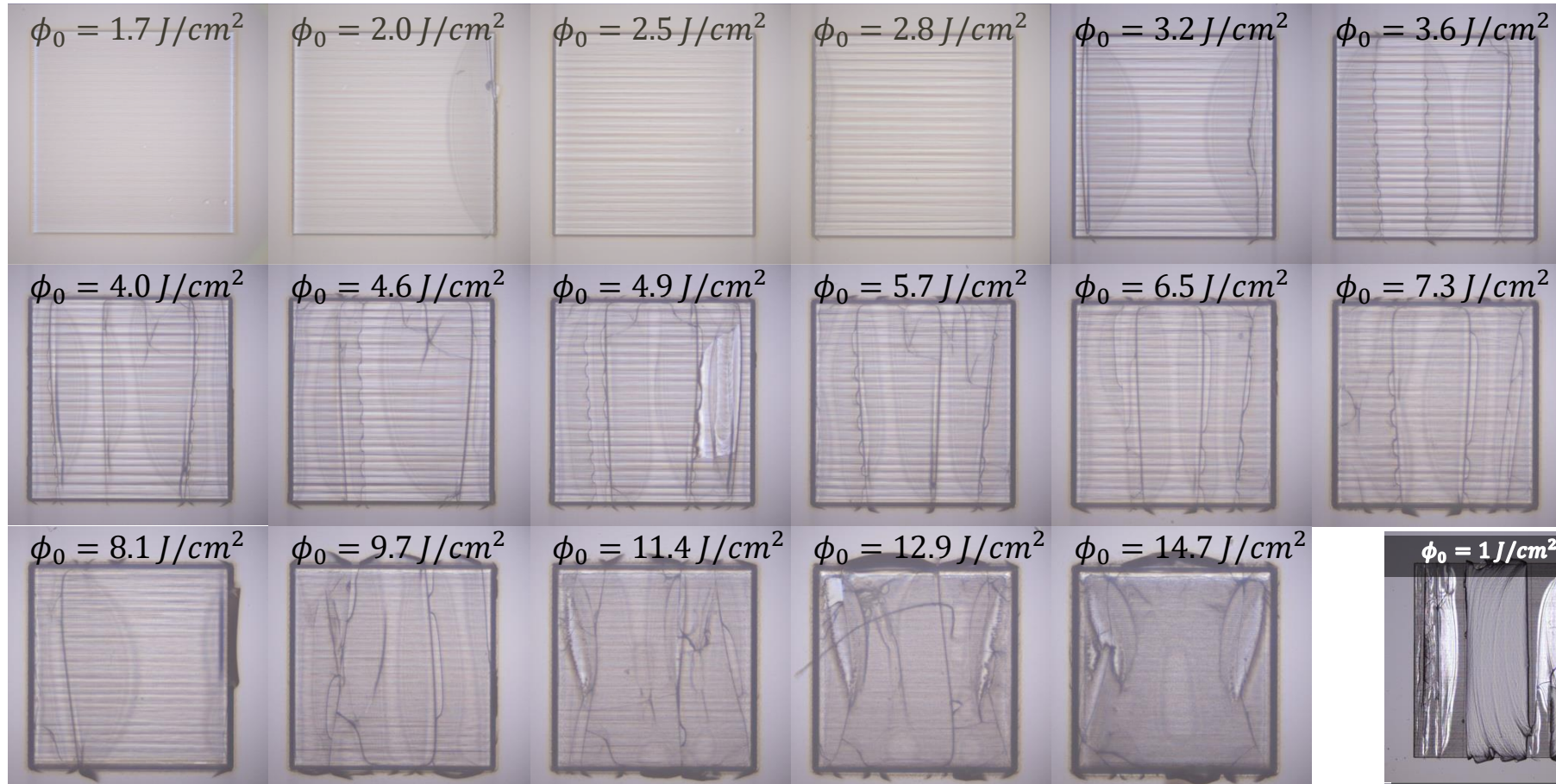
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- ▶ Roughness of the process stays almost constants for peak fluences above the threshold.
- ▶ Smaller for $\Delta\tau = 57 \text{ fs}$ and $\Delta\tau = 100 \text{ fs}$.
- ▶ Edge quality massively improved for shorter pulse durations $\Delta\tau = 57 \text{ fs}$ and $\Delta\tau = 100 \text{ fs}$.
- ▶ No visible chipping for $\Delta\tau = 57 \text{ fs}$ and $P_{av} = 23.3 \text{ W}$.
- ▶ Line Roughness strongly decreases for short pulses
- ▶ Sub 100 fs pulses lead to high edge quality also at high average powers.

Carbide: Sapphire

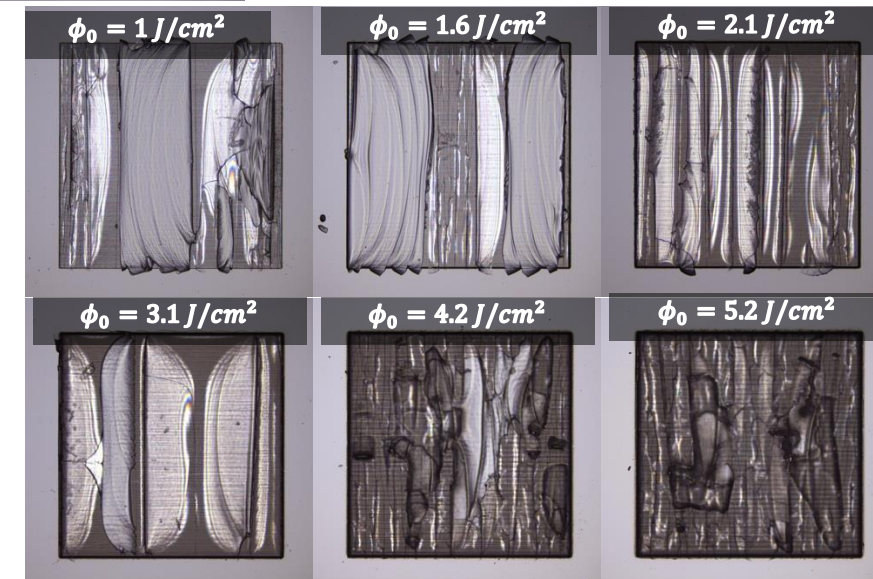


- ▶ Edge quality increases for shorter pulse durations.
- ▶ Almost no chipping for $\Delta\tau = 57 fs$ and $P_{av} = 28 W$.
- ▶ Sub 100 fs pulses lead to high edge quality also at high average powers.

Pharos: NSF2, $\Delta\tau_{Gauss} = 57 fs$



cf. Satsuma 515 nm, 350 fs



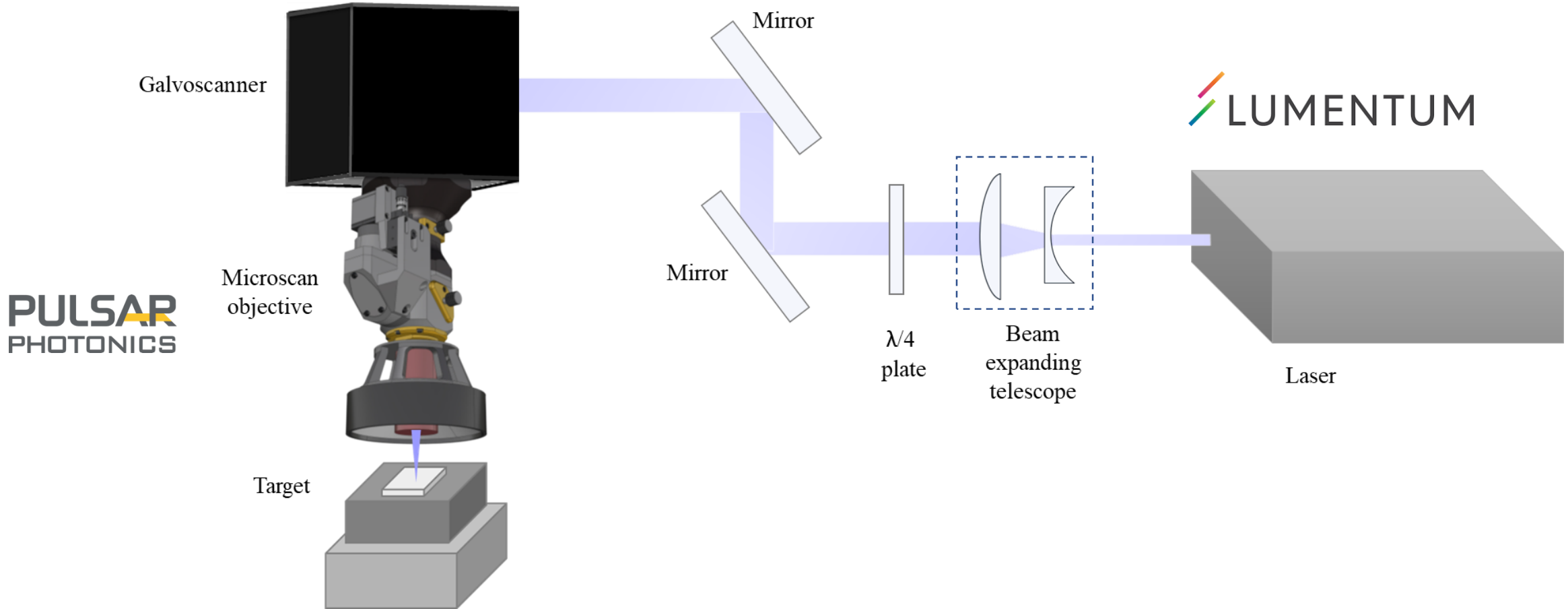
- ▶ Cracking strongly reduced for 57 fs pulses at 1030 nm.
- ▶ Even some squares without or with almost no cracks.



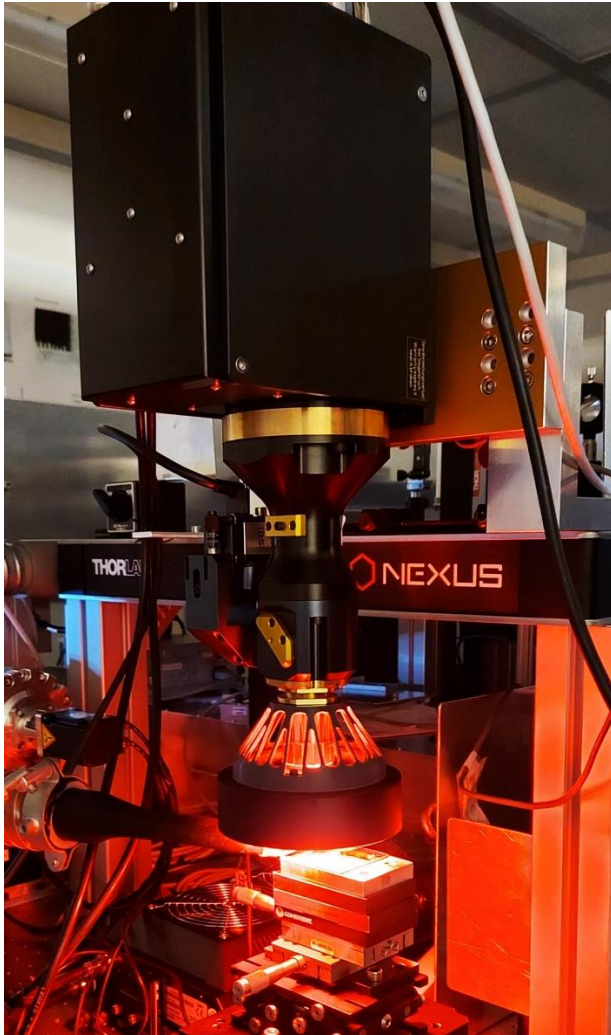
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Super Small

Experimental Setup

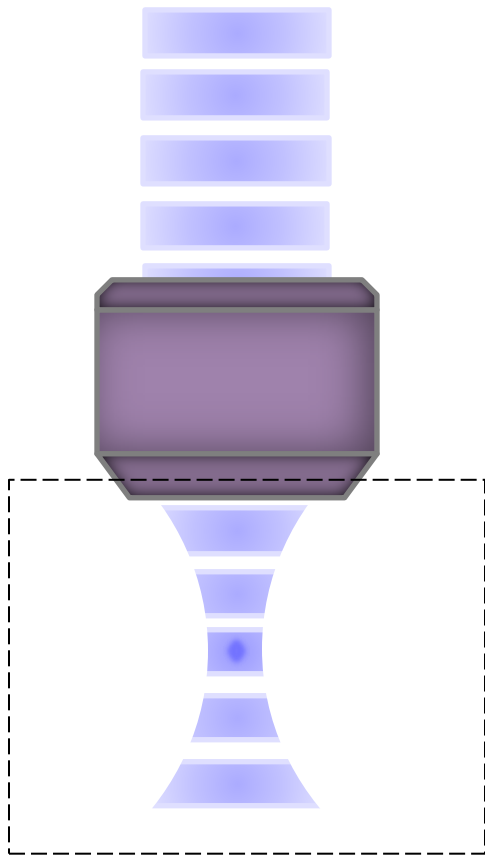


Experimental Setup

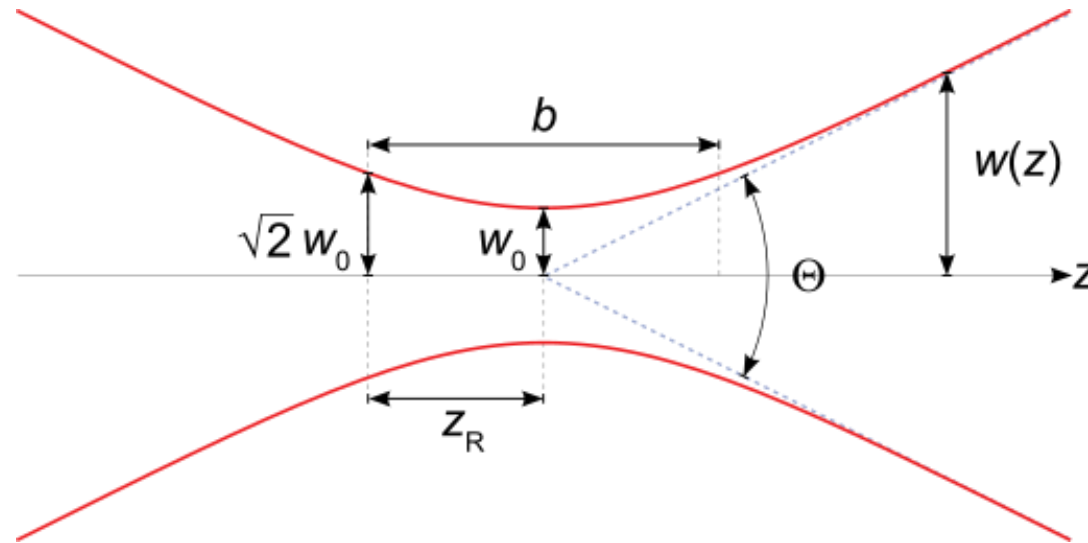
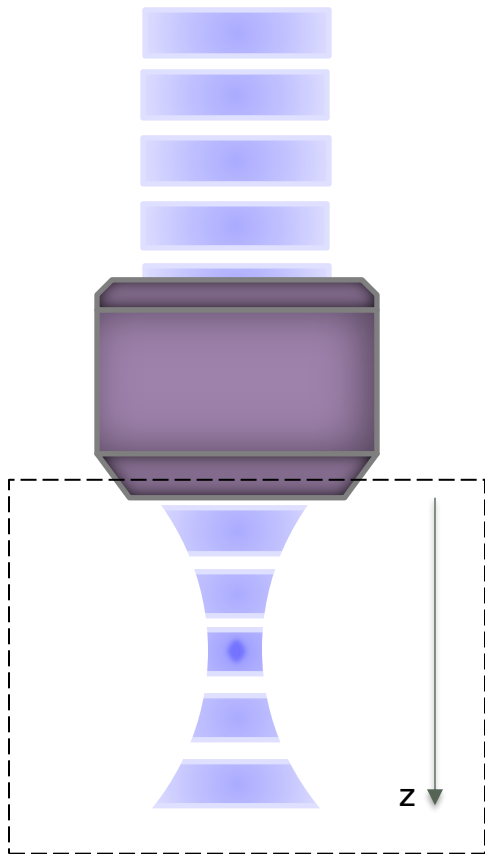


- ▶ Laser: Fuego UV
 - ▶ $\lambda = 355 \text{ nm}$
 - ▶ $\Delta\tau = 10 \text{ ps}$
 - ▶ $f_{\text{rep}} = 0.2 - 2 \text{ MHz}$
- ▶ Galvo scanner: SCANLAB IntelliSCANde14
 - ▶ Synchronized on the laser pulse train
- ▶ Objective: Microscan Obj. UV (Pulsar Photonics)
 - ▶ $f_{\text{obj}} = 10 \text{ mm}$
 - ▶ $2 \cdot w_0 < 1.5 \mu\text{m}$
- ▶ Smallest Structures:
~of the order of the beam spot diameter

Rayleigh Range



Rayleigh Range



Gaussian beam width

$$w(z) = w_0 \sqrt{1 + \left(\frac{z}{z_R}\right)^2}$$

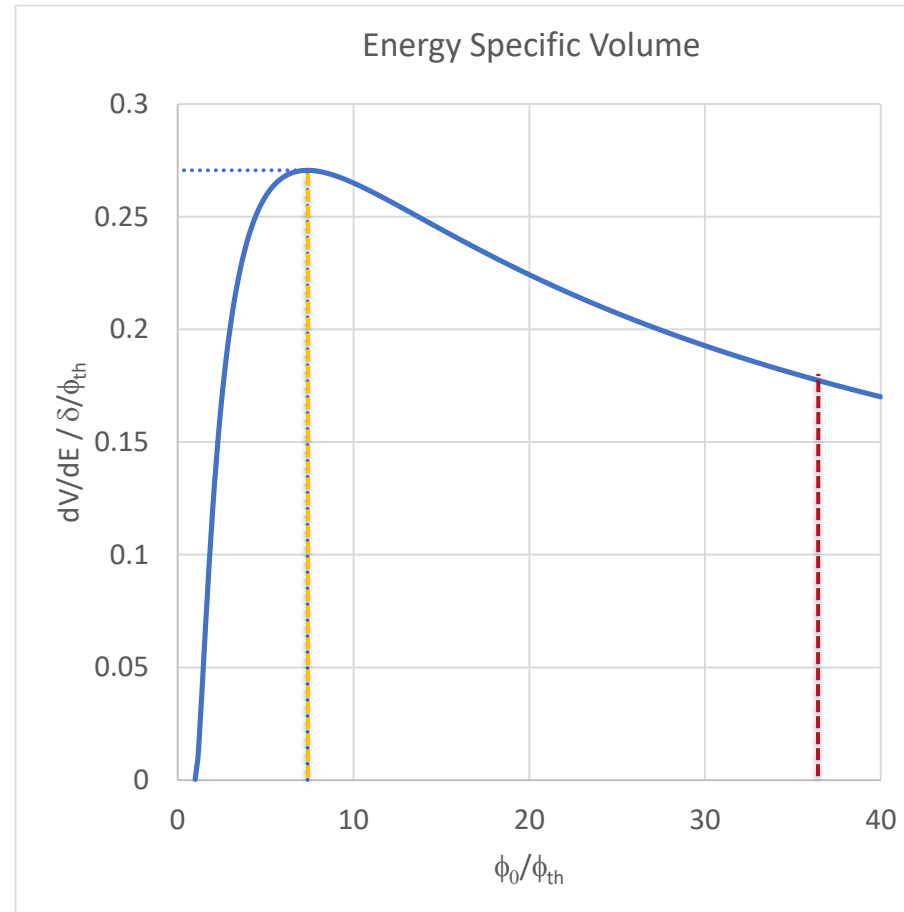
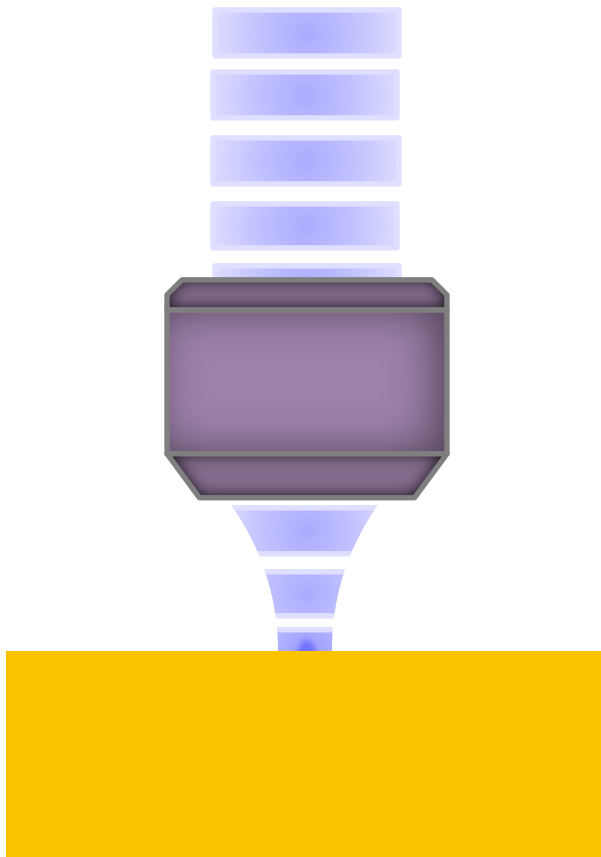
Rayleigh length

$$z_R = \frac{\pi w_0^2}{\lambda}$$

Microscan Objective, $z_R \sim 5 \mu m$

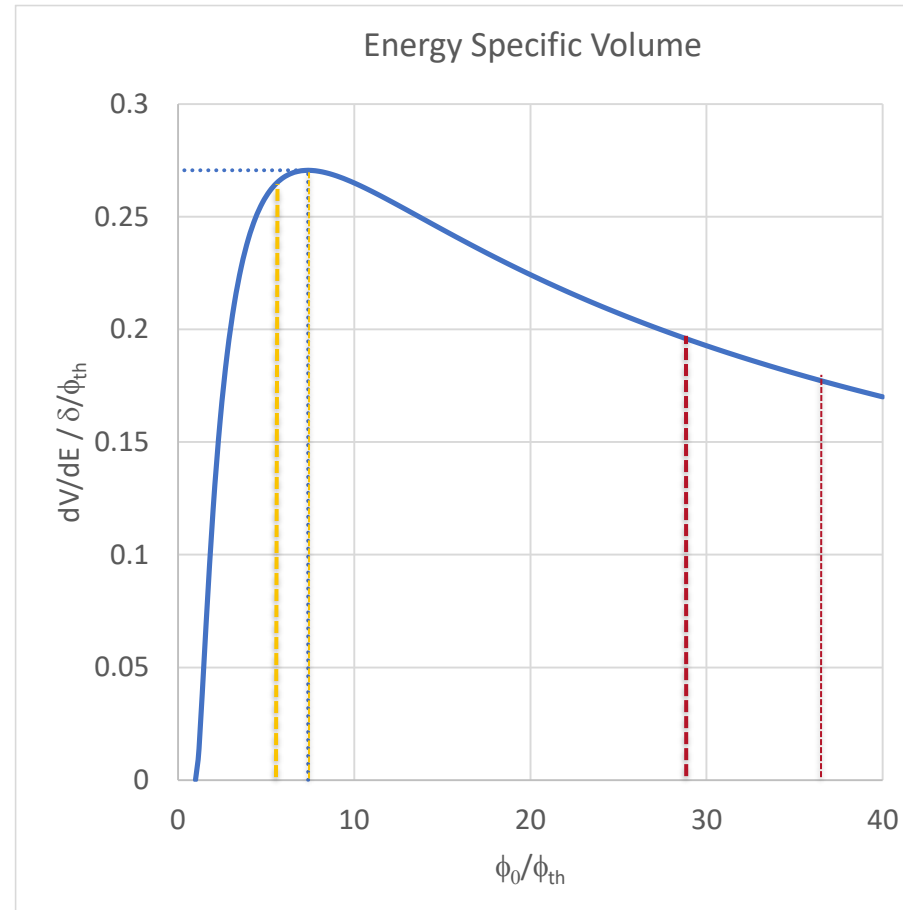
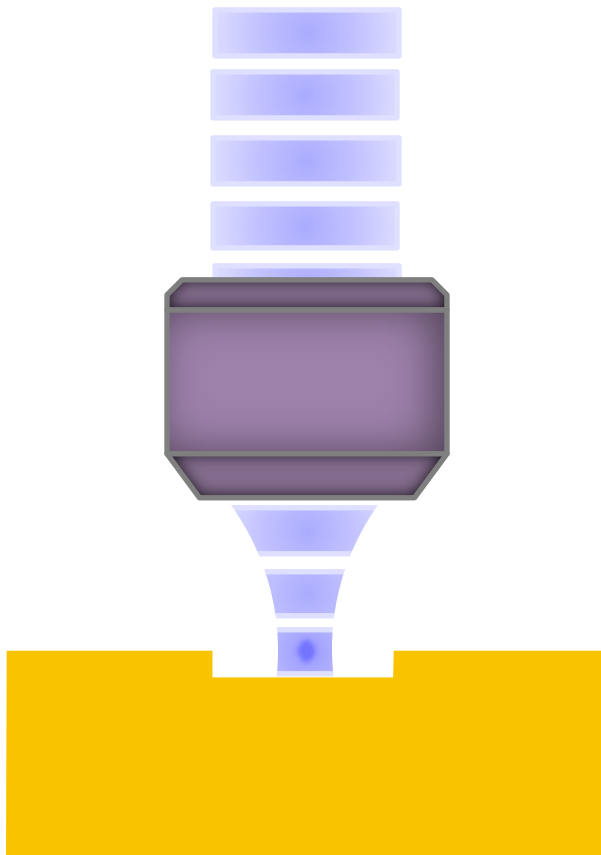
<https://commons.wikimedia.org/w/index.php?curid=6002103>

Rayleigh Range



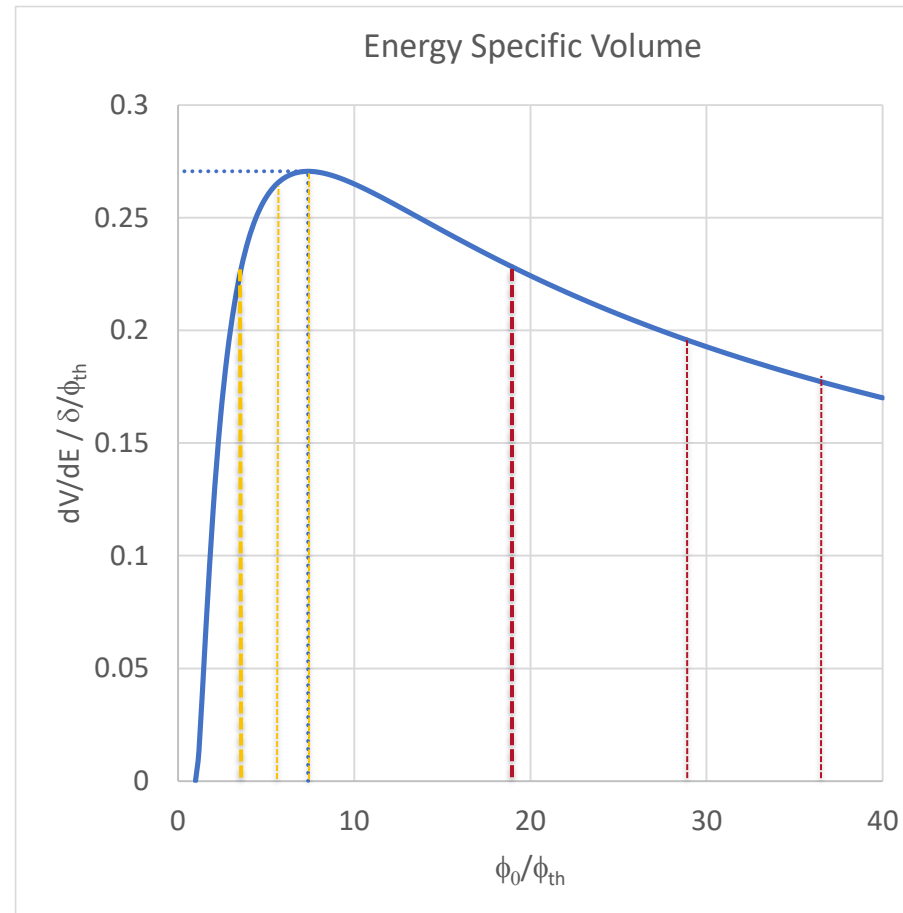
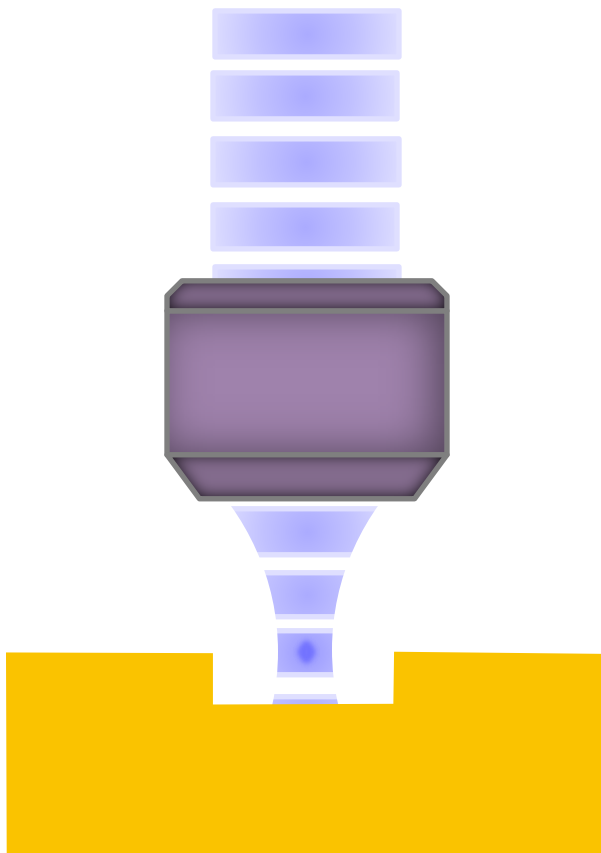
- ▶ Depending on the ablation depth the beam radius changes
- ▶ In case of a short Rayleigh length this can become significant.

Rayleigh Range



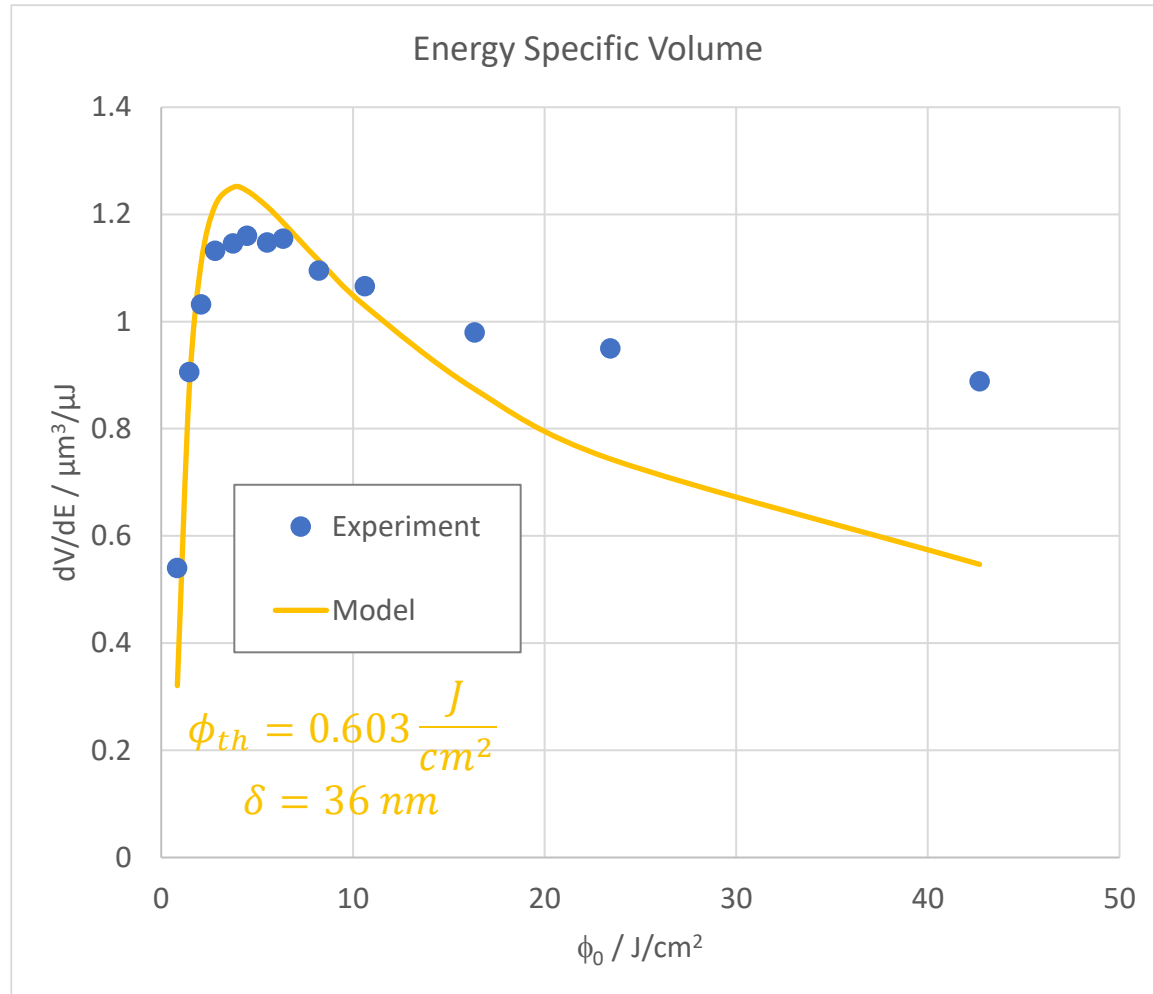
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- ▶ And leads to an increase (red) or decrease (yellow) of the energy specific volume

Rayleigh Range



- ▶ Depending on the ablation depth the beam radius changes
- ▶ In case of a short Rayleigh length this can become significant.
- ▶ And leads to an increase (red) or decrease (yellow) of the energy specific volume.
- ▶ The structures become deeper or less deep than expected (or the work piece has to be shifted)
- ▶ Adaption of the model might be needed

Model for short Rayleigh Length



► Model:

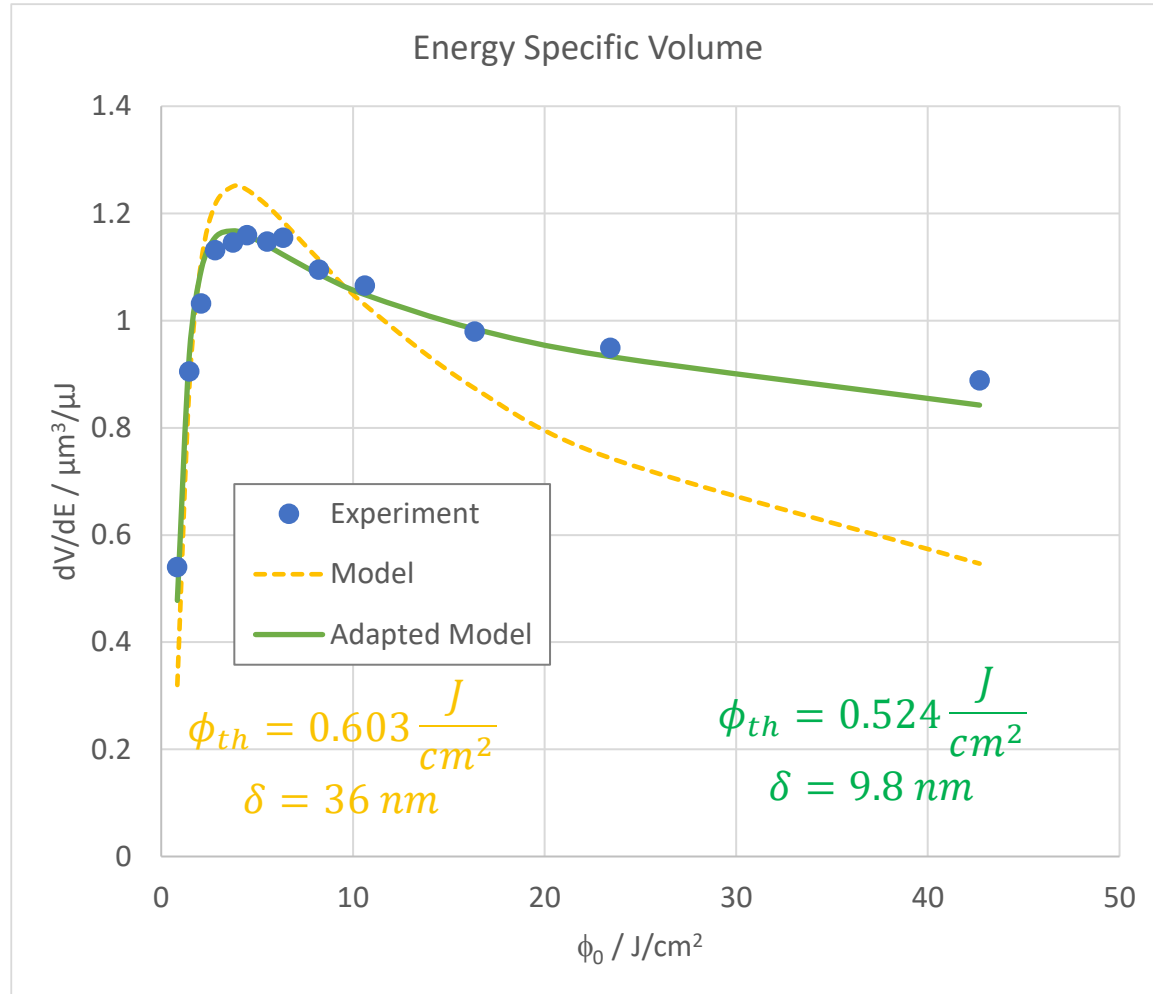
$$\frac{dV}{dE} = \frac{1}{2} \cdot \frac{\delta}{\phi_0} \cdot \ln^2 \left(\frac{\phi_0}{\phi_{th}} \right)$$

► As expected, deeper squares at high fluences and therefore higher energy specific volume compared to the model.

► Adapted Model:

- Calculate ablation depth for first layer
- Adapt spot size resp. ϕ_0 accordingly
- Repeat for each layer and calculate the full depth
- Then calculate the energy specific volume
- Least square fit for ϕ_{th} and δ

Model for short Rayleigh Length



► Model:

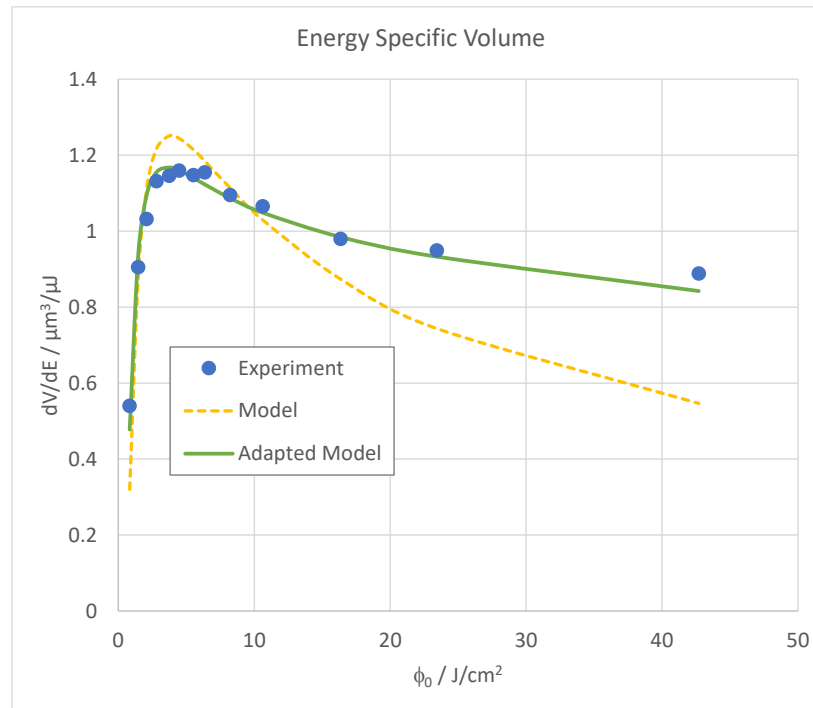
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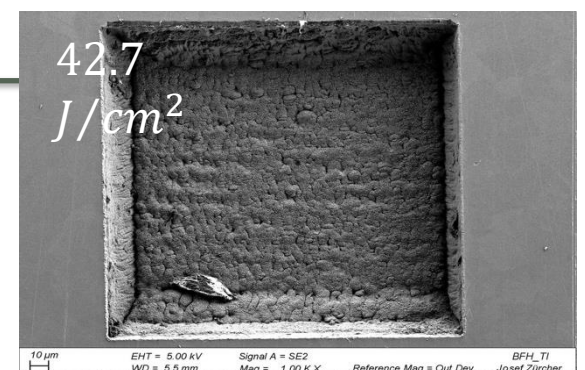
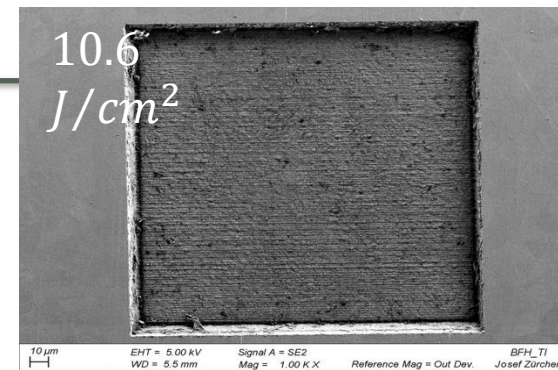
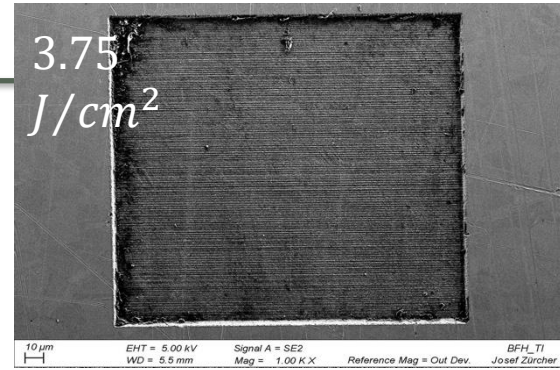
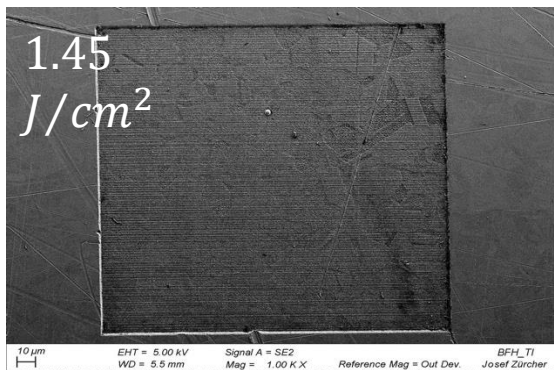
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Steel AISI 304, $\Delta\tau = 10 \text{ ps}$, $\lambda = 355 \text{ nm}$, $w_0 = 0.77 \text{ }\mu\text{m}$, $N_{SL} = 10$

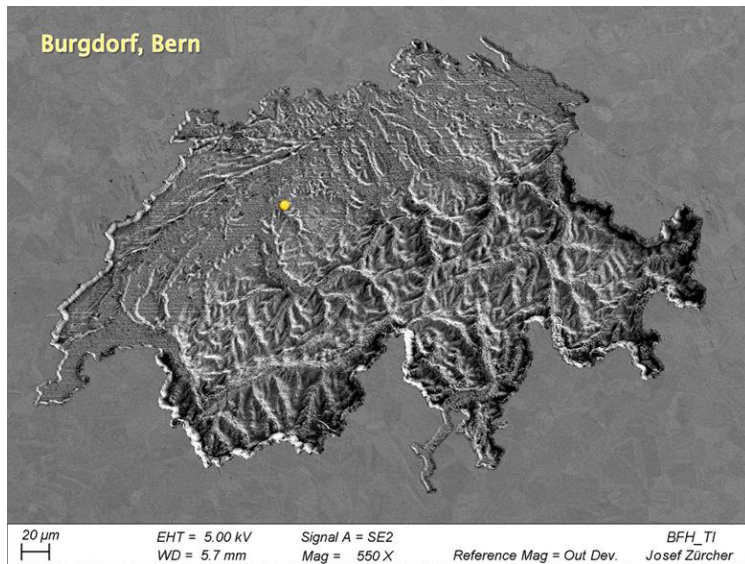


- ▶ No formation of CLP observed, also not for very high peak fluences

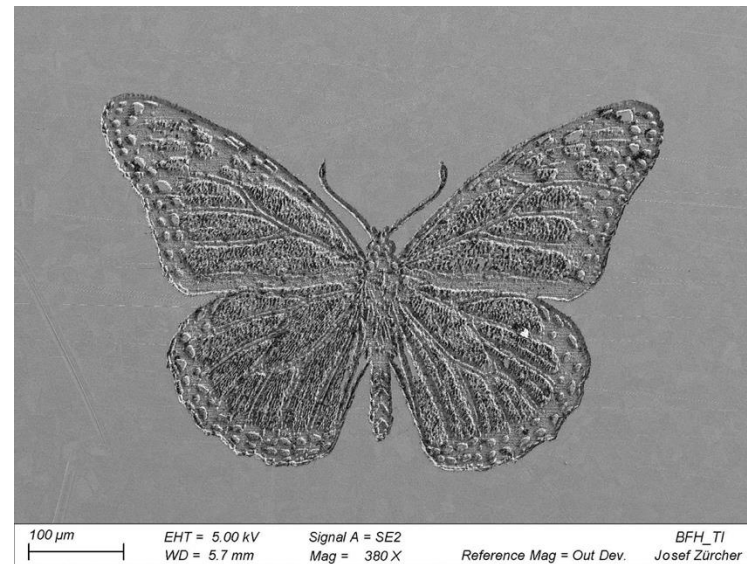


Some Examples

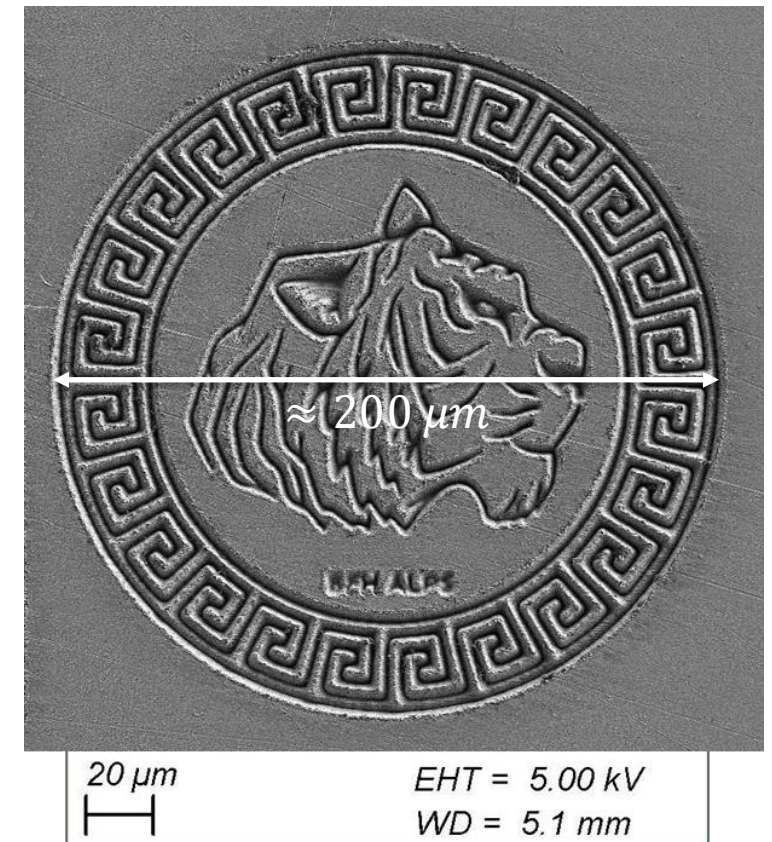
Micro-Swiss in Steel



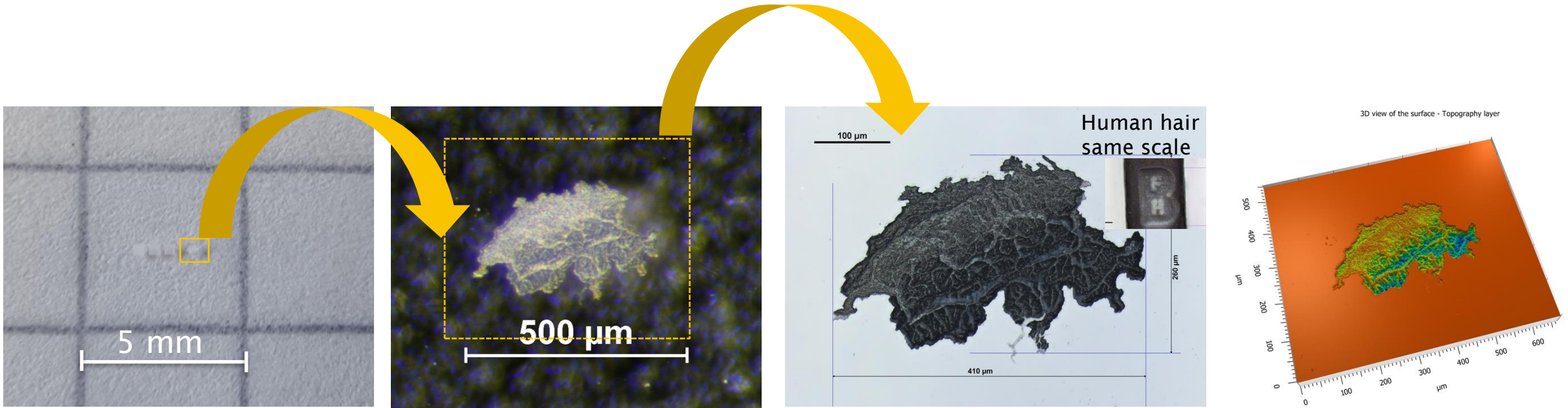
Butterfly in Steel



Structure in Copper

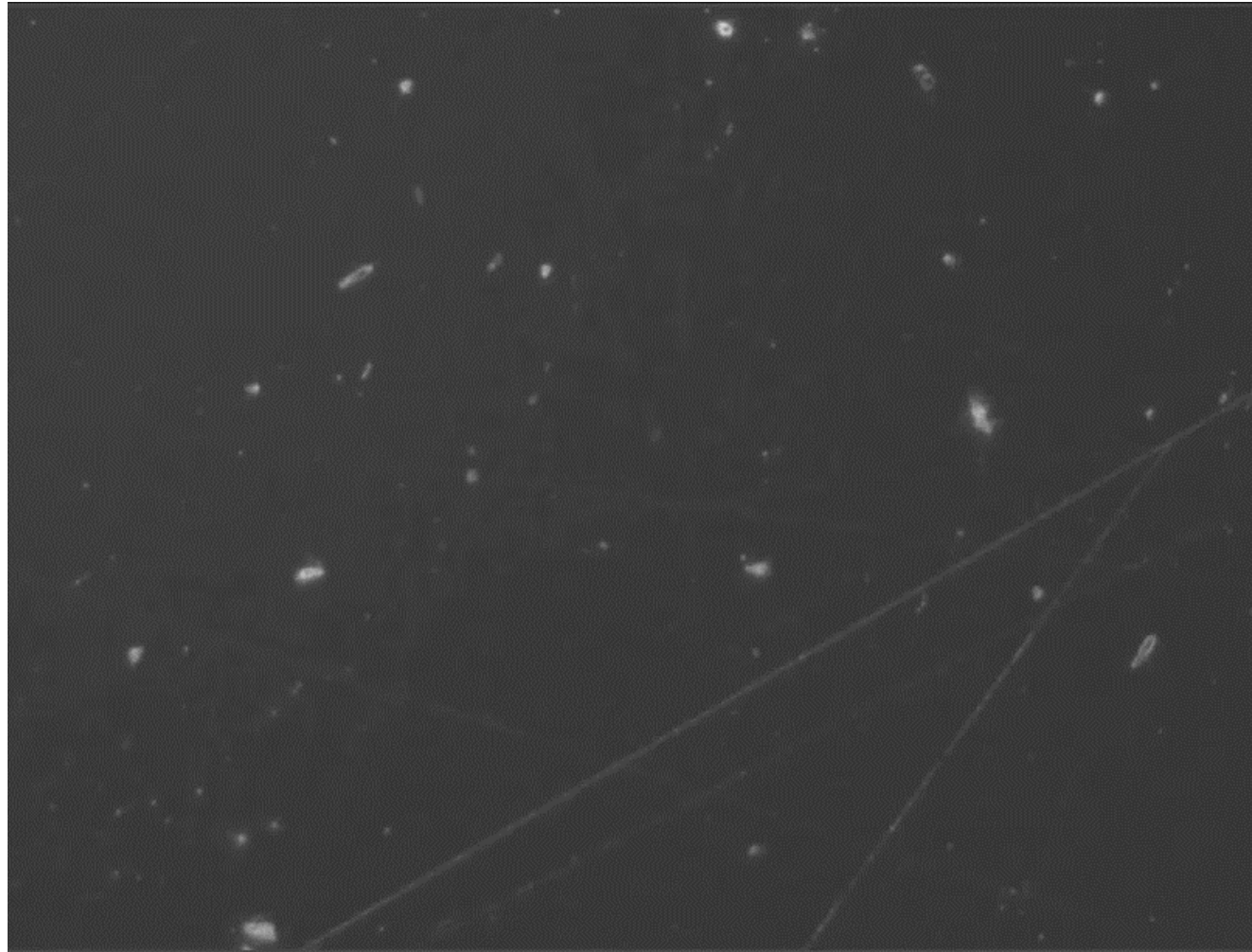


Extreme Precision: Small Spots



- ▶ Topographic map of Switzerland machined in sapphire with a scale of 1:850'000'000.
- ▶ Dimension: 410 µm x 220 µm with maximum depth of 20 µm.
- ▶ A disruptive technology in laser micromachining for highest precision and resolution.
- ▶ Applications: Almost invisible security features, watches and jewelry, functional surfaces.

Video (8x) of Machinig Switzerland's Topography



Summary

▶ Super Short:

- ▶ The regime of sub 100 fs pulses with an industrial grade set up was investigated in an explorative study concerning ablation efficiency, surface roughness and edge quality.
- ▶ Metals, tungsten carbide, PCD, Zirconia and other ceramics (all not shown here): No significant improvement
- ▶ Glasses: Massively improved edge quality and reduced roughness at similar energy specific volumes.
- ▶ Investigations ongoing

▶ Super small:

- ▶ Microspot scanning system tested and very precise structures machined
- ▶ No cavity formation in steel in UV with microscan
- ▶ Limiting factor - Rayleigh range



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Thank you very much for your kind attention